

FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MICRON.182A	APPLICATION NO. 09/973,854
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		O I P E FEB 11 2002 APPLICANT: Chopra et al.	
(USE SEVERAL SHEETS IF NECESSARY)		FILING DATE October 9, 2001	GROUP 1765
		COPY OF PAPERS ORIGINALLY FILED	

U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

FOREIGN PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES NO

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
JM	A	Dinesh Chopra and Ian Ivar Suni, "An Optical Method for Monitoring Metal Contamination during Aqueous Processing of Silicon Wafers", <i>J. Electrochem. Soc.</i> , Vol. 145, No. 5, May 1998, pp. 1688-1692.
JM	B	Dinesh Chopra, Ian Ivar Suni and Ahmed A. Busnaina, "Cu Dissolution from Si(111) into an SC-1 Process Solution", <i>J. Electrochem. Soc.</i> , Vol. 145, No. 4, April 1998, pp. L60-61.
JM	C	Peter Singer, Editor-in-Chief, "Copper CMP: A Question of Tradeoffs", Semiconductor International, http://www.semiconductor.net/semiconductor/issues/issues/2000/200005/six005cmp.asp , May 2000, 11 pages.
JM	D	"The CMP Business Unit", Rodel Products, http://www.rodel.com/Products/CMP.asp , 1998-2000, 13 pages.
JM	E	Kurt Hery and Dr. David P. Norwood, "Study of the Refractive Index Increment of Polyelectrolytes and Neutral Polymers", Southeastern Louisiana University, http://www.selu.edu/Academics/ArtsC/Sciences/connections/journal1/k-hery/Hery.html , 7 pages.
JM	F	Iqbal Ali and Sudipto R. Roy, "Pad conditioning in interlayer dielectric CMP", Texas Instruments, http://www.semipark.co.../Pad%20conditioning%20in%20interlayer%20dielectric%20CMP.htm , June 1, 1997, 6 pages.
JM	G	"Chemical Mechanical Planarization (CMP)", S.C. Solutions, http://www.scsolutions.com/smp.html , 4 pages.

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EXAMINER: <i>W.Hachter</i>	DATE CONSIDERED: <i>9/5/03</i>
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